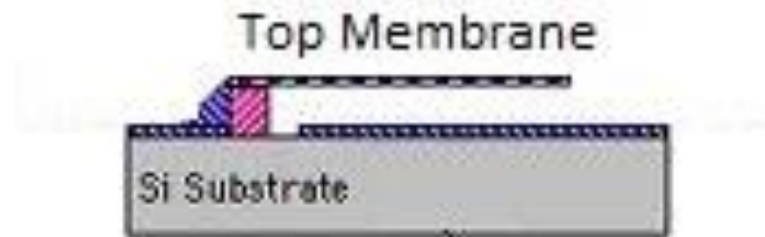




# Contact force analysis of MEMS Switches

# What is MEMS Switch?



(a) OFF State

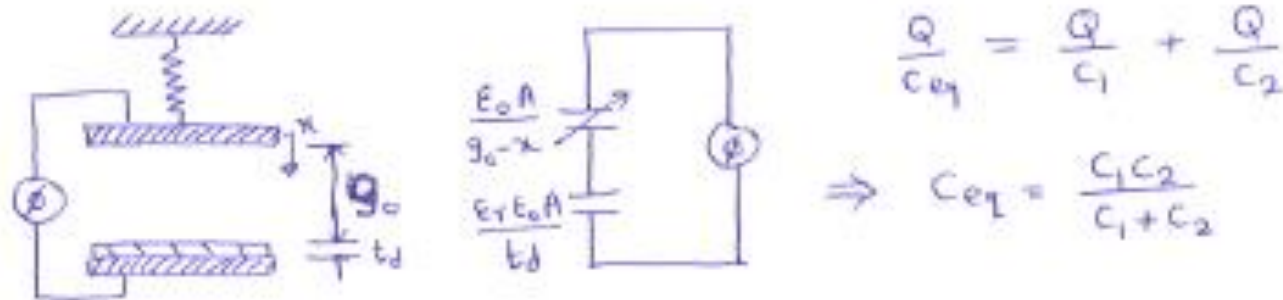


(b) ON State

# Derivation

The total energy of the cantilever beam and ground plate is given as,

$$\begin{aligned} T.E. &= S.E. - ESE_c \\ &= \frac{1}{2} kx^2 - \frac{1}{2} C_1 \phi^2 \end{aligned}$$



$$\frac{Q}{C_{eq}} = \frac{Q}{C_1} + \frac{Q}{C_2}$$

$$\Rightarrow C_{eq} = \frac{C_1 C_2}{C_1 + C_2}$$

$$\frac{\partial^2 (T.E.)}{\partial x^2} = 0 \quad \text{and} \quad \frac{\partial (T.E.)}{\partial x} = 0$$

$$\Rightarrow x = \frac{1}{3} \left( g_0 + \frac{t_d}{3} \right) \quad \Rightarrow \phi_{\text{Pull-in}} = \sqrt{\frac{9k \left( g_0 + \frac{t_d}{3} \right)^3}{27 E_0 A}}$$

The contact force is given as,

$$F = \frac{\epsilon_r^2 E_0 A \phi^2}{2 t_d^2} - k g_0$$

# Beam parameters & F v/s $\phi$ graph

$l=200 \mu\text{m}$

$b=20 \mu\text{m}$

$h=5 \mu\text{m}$

$g_0=20 \mu\text{m}$

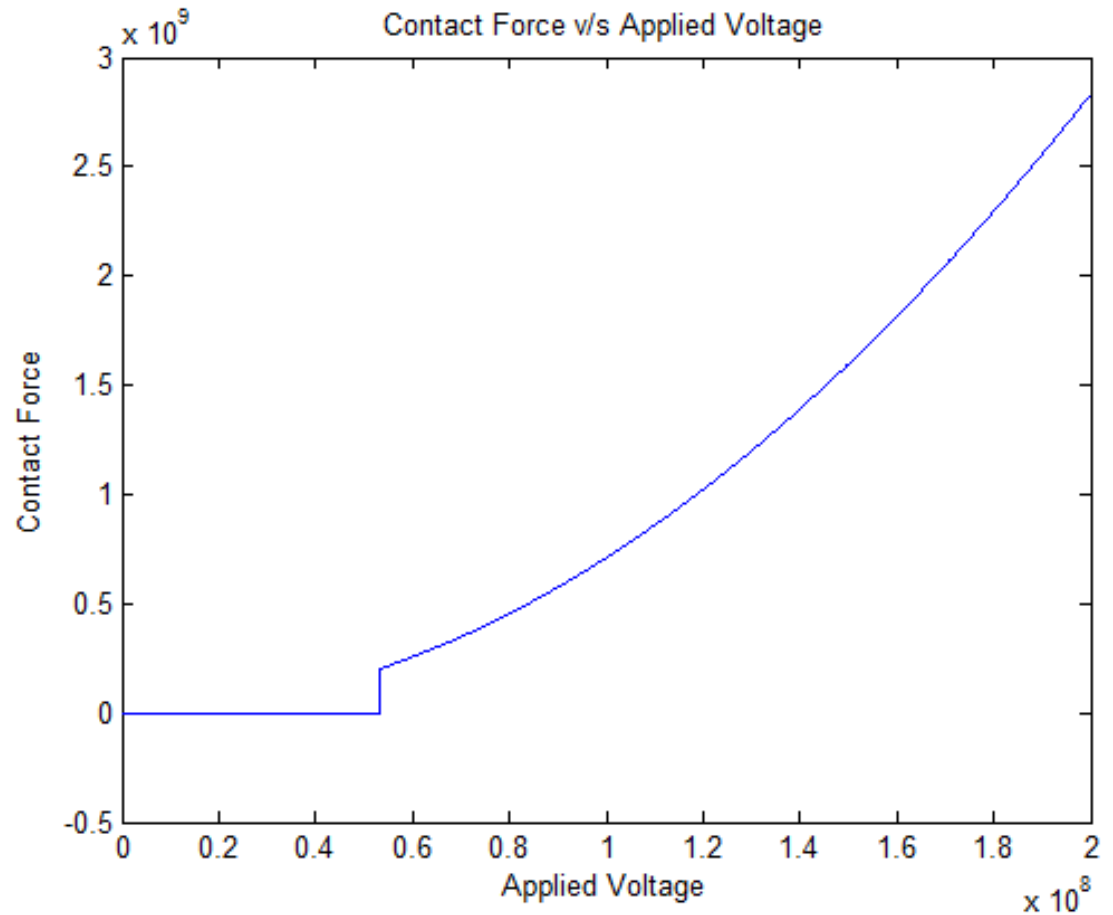
$t_d=2 \mu\text{m}$

$\epsilon_r=4$

$E=210 \text{ Gpa}$

$\phi_{\text{pull\_in}}$

$=5.3057e+07 \text{ V}$



# Conclusion

- Initially, contact force is zero till the voltage reaches  $\phi_{\text{pull in}}$ .
- After it, it increases suddenly and finally opts a parabolic path

# Advantages and Applications

- Very low insertion loss (loss of signal power resulting from the insertion of a device in a transmission line)
- Excellent signal linearity
- Lower power consumption compared to conventional electronic switches based on diodes, GaAs, FETs.
- Handset applications
- Radar systems for defense applications
- Satellite communication systems
- Wireless communication systems
- Instrumentation systems



**Thank you**